# Dobrý den,

jako zadavatel veřejné zakázky s názvem "Rastrovací Augerova mikroskopie – CEITEC MU" zasíláme tímto dodavatelům veřejné zakázky v souladu s ustanovením § 49 odst. 4 zákona č. 137/2006 Sb., o veřejných zakázkách, v platném znění, dodatečné informace č. 2 k zadávacím podmínkám.

Na základě reakce zadavatele na dodatečné informace č. 1 (znění dodatečných informací č. 1 - viz. příloha této zprávy), poskytuje zadavatel těmito dodatečnými informacemi č. 2 odpovědi na dotazy uchazeče Měřící technika Morava s.r.o., se sídlem 1. máje 102, 664 84 Zastávka, IČ: 29316715, položených prostřednictvím dodatečných informací č. 1.

#### Dotaz uchazeče č. 1:

In the line Fast entry chambre you wrote: "Fast entry chamber is used to introduce and to transport samples into the analytical chamber without breaking vacuum. Fast entry chamber and analytical chamber are separated by a valve and interlock."

Question: Do we understand the specification right if we assume it would be fulfilled by a system that has a manual gate valve between the fast entry chamber and the analytical chamber as a separation and an interlock for vacuum protection between the analytical chamber and the pumping system?

### Odpověď zadavatele:

Yes, the interlock for vacuum protection between the analytical chamber and the pumping system is sufficient. The valve between the fast entry chamber and the analytical chamber can be manually operated.

## Dotaz uchazeče č. 2:

In the line Sample holder you wrote: "The sample holder has at least four electrical contacts, the sample can also be connected to two impedance matching wires with connectors for the transmission of high frequencies up to 6 GHz at least."

Question: Do we understand the specification right if we assume it would be fulfilled by connectors which are rated for 6 GHz? We will confirm the specifications by providing the specifications sheet of the third party provider.

# Odpověď zadavatele:

Yes, the specifications will be fulfilled by supplying connectors rated for 6 GHz.

### Dotaz uchazeče č. 3:

In the line Beam current you wrote: "The beam current in a minimum of 50 nA at an energy of 15 keV and a resolution of 12 nm and 28 nA at 3 keV energy with resolution 18 nm. Resolution measured by 20% - 80%."

Question: Do we understand the specification right if this is a general third party vendor specification and we prove this resolution by dark apace resolution on a Au-C sample during the acceptance test?

### Odpověď zadavatele:

Yes, the demonstration of the resolution on the on an Au-C sample is acceptable.

#### Dotaz uchazeče č. 4:

In the line Detection you wrote: "The total pulse counting detection with > 70 Mcps (Mega counts per second) integral count rate for a minimum of 7 channels and variable slit mechanism for optimisation of the resolution."

Question: Do we understand the specification right if the >70 Mcps integral count rate is a general specification of the analyzer? During the acceptance test we would show the following:

Intensity > 12000 cps per nA and channel for the 352 eV Ag peak at CRR 4 (0.5% resolution), i.e.

> 420 000 cps for typical configuration (5 nA, 7 channels)

Intensity at 5 keV primary beam energy, with sample tilt 30°\* with respect to primary beam, ion-sputtered Ag sample bulk material. Working distance: 8 mm. Beam current measured using a Faraday-cup.

Signal is: peak intensity minus background.

# Odpověď zadavatele:

Yes, the acceptance test described in the question is sufficient.

### Dotaz uchazeče č. 5:

In section SEM, SAM in the line Image drift you wrote: "Image drift is <10 nm/10 hours. The system alows controlled compensation of the drift."

And in the section SEMPA, line Image drift you wrote: "Size of image drift <10 nm/10 hours. The system allows control drift compensation. "

Question: Do we understand the specification right if we assume it would be fulfilled by having image features staying in a radius of 10 nm in 10 hrs as shown on the screen image during the acceptance?

# Odpověď zadavatele:

Yes, the image drift can be demonstrated by having the image features staying in a radius of 10 nm as shown on the screen.

S pozdravem

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